Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Previously presented) An integrated circuit, comprising:

an array of ferroelectric memory cells, each cell having a capacitor stack having a single ferroelectric core layer with a crystallization in the (001) family, wherein at least 40% of the domains of the single ferroelectric core layer are functionally oriented with respect to the capacitor stack, and wherein at least one of the capacitor stacks comprises a conductive contact formed thereover or thereunder, or both, and wherein the conductive contact has a cross section near a contact portion with the top portion of the stack, the bottom portion of the stack, or both, that is about as large or larger than that of the ferroelectric cores.

- (Original) The integrated circuit of claim 1, wherein from about 45 to about 75% of the domains are functionally oriented with respect to the capacitor stack.
- 3. (Original) The integrated circuit of claim 1, wherein the ferroelectric cores are PZT cores and the PZT of each core has a switched polarization of at least about 60 μ C/cm².
- (Previously presented) The integrated circuit of claim 1, further comprising:

a dielectric layer covering the array of memory cells, the dielectric layer having a conductive contact over each ferroelectric core, the conductive contacts each having a cross section about as large or larger than that of the ferroelectric cores.

- (Original) The integrated circuit of claim 1, wherein electrodes adjacent opposing sides of the ferroelectric cores have a collective thickness of at least about 200 nm thick.
- (Previously presented) The integrated circuit of claim 1, wherein each of
 the capacitor stacks are formed over conductive contacts, the conductive contacts each
 having a cross section near their top that is about as large or larger than that of the
 ferroelectric cores.

7-20. (cancelled)

21. (New) The integrated circuit of claim 1, further comprising:

a dielectric layer covering the array of memory cells, the dielectric layer having a conductive contact over each ferroelectric core, the conductive contacts each having a cross section about as large or larger than that of the ferroelectric cores and extending through said dielectric layer to a metal interconnect layer.